



Attorney's Docket No.: 77/213002 / US3521/3522

6/1/01
Cheresa
5-2-01

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Ohtani, et al. Art Unit : 2815
Serial No.: 09/455,991 Examiner : Jose R. Diaz
Filed : December 6, 1999
Title : SEMICONDUCTOR DEVICE AND METHOD OF MANUFACTURING
THE SAME

Commissioner for Patents
Washington, D.C. 20231

RESPONSE

In response to the action mailed November 21, 2000, please
amend the application as follows:

In the claims:

Please amend claims 6-12 as follows:

RECEIVED
MAY - 1 2001
TC 2800 MAIL ROOM

6. (Amended) A method of manufacturing a semiconductor
device, said method comprising:
forming an amorphous semiconductor film on an
insulating surface;

A1
sub B1

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this
correspondence is being deposited with the
United States Postal Service as first class mail
with sufficient postage on the date indicated
below and is addressed to the Commissioner for
Patents, Washington, D.C. 20231.

April 23, 2001

Date of Deposit

Signature

Nancy Grant

Nancy Grant

Typed or Printed Name of Person Signing
Certificate